

Nanophotonic lab-on-a-chip platforms including novel bimodal interferometers, microfluidics and grating couplers

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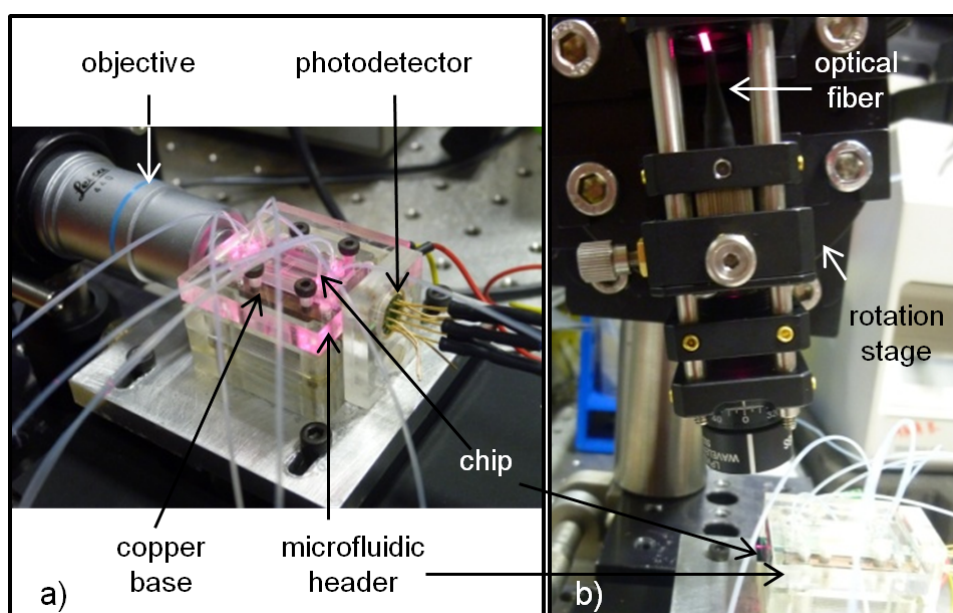


Fig. S1 Photographs of the set-up based on (a) end-fire method and (b) grating coupler method.

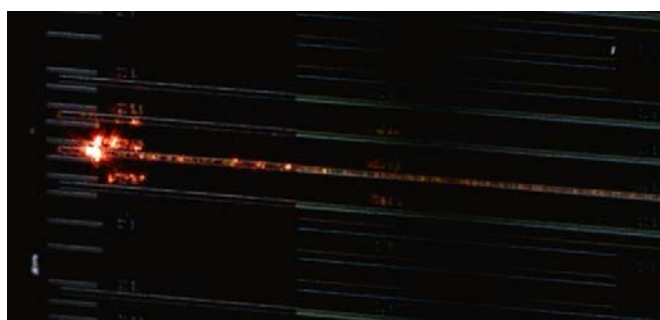


Fig. S2 Photograph of the BiMW chip highlighting the excited grating and the light propagating in the WG.

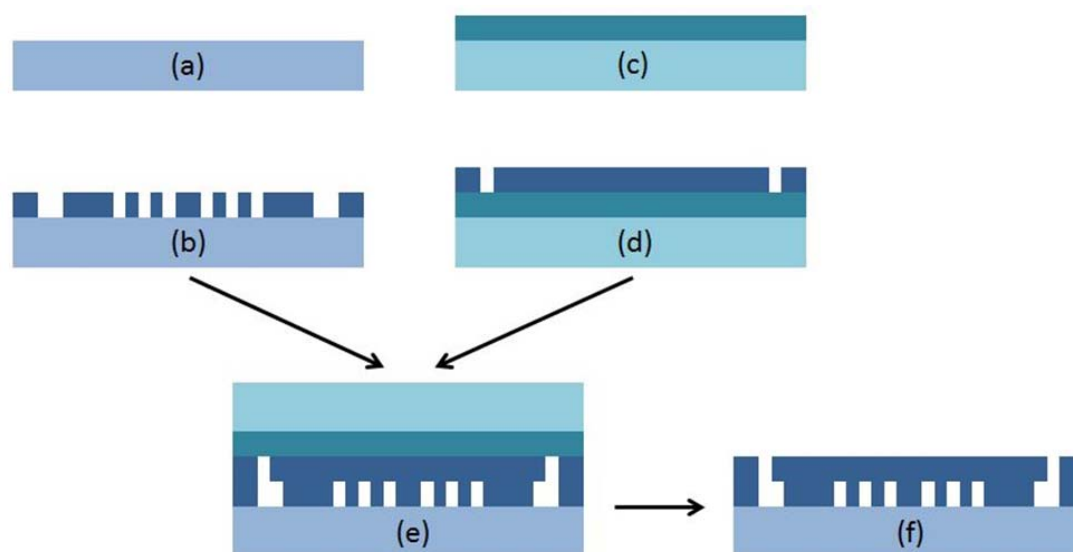


Fig. S3 Microchannel fabrication process flow: (a) spinning of SU-8 to reach a 50 μm thick layer, (b) microchannel definition using photolithography, (c) kapton wafer with a 40 μm thick SU-8 layer on top (d) Cover definition by photolithography, (e) bonding step, (d) kapton wafer release